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RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2881

PATENT

Dkt. No.: 29273/559

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS: Yuko IWABUCHI, et al.
SERIAL NO.: 10/083,481
FILED: February 27, 2002
FOR: METHOD AND AN APPARATUS OF AN INSPECTION SYSTEM
USING AN ELECTRON BEAM
GROUP ART: 2881
EXAMINER: Jack I. Berman

ASSISTANT COMMISSIONER FOR
PATENTS AND TRADEMARKS
Washington D.C. 20231

RESPONSE TO OFFICE ACTION

Sir:

In response to the Office Action dated January 7, 2003, please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel claims 2, 3, 14 and 15.

Please amend claims 1, 4, 9 and 16 as follows:

1. (Amended) An inspection method for detecting a defect of a specimen by using an electron beam, said method comprising the steps of:
deflecting said electron beam set at least 100nA beam current by taking a crossover as a fulcrum;
applying a retarding voltage for decelerating the electron beam to said specimen; and
changing the magnitude of said retarding voltage based on the nature of said specimen.

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